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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	I amount		
09/593,358	06/14/2000		THI GRAET BOCKET NO.	CONFIRMATION NO.	
07/373,338	06/14/2000	Willard L. Hofer	MICS.0053	8367	
	590 12/03/2002				
Michael G Fisher Fletcher Yoder & Van Someren			EXAMINER		
Houston, TX 77269-2289			TOO I EIV, JIMMY I		
			ART UNIT	PAPER NUMBER	
			2829		
			DATE MAILED: 12/03/2002		

Please find below and/or attached an Office communication concerning this application or proceeding.

		Application No.	Applicant(s)	
Office Action Summary				1 6
		09/593,358	HOFER ET AL.	
	omes Adden Sammary	Examiner	Art Unit	
	The MAILING DATE of this communication app	Jimmy Nguyen	2829	nee
Period fo		sears on the cover sheet with the t	orrespondence adure	:55
THE N - Exter after - If the - If NO - Failui - Any r	ORTENED STATUTORY PERIOD FOR REPL MAILING DATE OF THIS COMMUNICATION. Isions of time may be available under the provisions of 37 CFR 1.1 SIX (6) MONTHS from the mailing date of this communication. period for reply specified above is less than thirty (30) days, a repl period for reply is specified above, the maximum statutory period to reply within the set or extended period for reply will, by statute eply received by the Office later than three months after the mailing d patent term adjustment. See 37 CFR 1.704(b).	36(a). In no event, however, may a reply be ting within the statutory minimum of thirty (30) day will apply and will expire SIX (6) MONTHS from a cause the application to become ABANDONE	nely filed vs will be considered timely. the mailing date of this committed to the committed to the committed that the commit	nunication.
1)	Responsive to communication(s) filed on 9/9/	/02		
2a)□	,	oz. nis action is non-final.		
3)	Since this application is in condition for allows closed in accordance with the practice under	ance except for formal matters, p		nerits is
Dispositi	on of Claims			
4)🖂	Claim(s) 1-7 is/are pending in the application.			
•	4a) Of the above claim(s) is/are withdra	wn from consideration.		
5)	Claim(s) is/are allowed.			
6)⊠	Claim(s) <u>1-7</u> is/are rejected.			
7)	Claim(s) is/are objected to.			
8)[Claim(s) are subject to restriction and/o	r election requirement.		
Applicati	on Papers			
9) 🗌 -	Γhe specification is objected to by the Examine	er.		
10) 🔲 🛚	The drawing(s) filed on is/are: a)☐ acce	pted or b)⊡ objected to by the Exa	miner.	
	Applicant may not request that any objection to the			
11) 🔲 🛚	The proposed drawing correction filed on		oved by the Examiner.	
_	If approved, corrected drawings are required in re			
•	The oath or declaration is objected to by the Ex	raminer.		
-	nder 35 U.S.C. §§ 119 and 120			
<i>,</i> —	Acknowledgment is made of a claim for foreign	n priority under 35 U.S.C. § 119(a	ı)-(d) or (f).	
a)[☐ All b)☐ Some * c)☐ None of:			
	1. Certified copies of the priority document			
	Certified copies of the priority document	• •		
	 Copies of the certified copies of the prior application from the International Bute ee the attached detailed Office action for a list 	reau (PCT Rule 17.2(a)).		ige
	cknowledgment is made of a claim for domesti	•		plication).
	☐ The translation of the foreign language pro			•
•	cknowledgment is made of a claim for domest			
Attachment	(s)			
2) 🔲 Notice	e of References Cited (PTO-892) e of Draftsperson's Patent Drawing Review (PTO-948) nation Disclosure Statement(s) (PTO-1449) Paper No(s) _	-	(PTO-413) Paper No(s). Patent Application (PTO-1	

Art Unit: 2829

DETAILED ACTION

Response to Argument

The response filed 9/18/02 has been carefully considered with the following effect;

The examiner agrees on the argument of the Sundar et al (6283701) reference, on the other hand, the examiner disagrees on the secondary reference of Matsukawa et al (US 5518542). Matsukawa et al teach (fig 7) the holding structure 911a, 11b) arranged to hold the wafer and rotate the wafer as disclosed in column 6 line 51 - 64. The arm-rotating shaft 102 will rotate the section 110 and the holding arms 111a and 111b.

Regarding the rotation of the first axis, upon further search the examiner makes new rejection as below.

Claim Rejections - 35 USC § 103

- The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all 1. obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- Claims 1-7 are rejected under 35 U.S.C. 103(a) as being unpatentable over 2. Becker et al (US 6186873) in view of Matsukawa et al (US 5518542)

Application/Control Number: 09/593,358

Art Unit: 2829

Regarding claim 1, Becker et al disclose (fig 1)

A holding structure (10) having members (93) arranged to hold and rotate (column 2, line 30 –33 and column 2 line 51 –55, it is driven by tow idler gears 14, 15, 12) the substrate (20) about a first axis, the holding structure (10) being coupled to a rotatable member

However, Becker et al is silent on the rotable member configured to rotate the holding structure about a second axis different from the first axis.

On the other hand, Matsukawa et al teach on the rotable member configured to rotate the holding structure (111a, 111b) about a second axis (flipping) different from the first axis for the purpose of providing the ability for testing system to test the wafer from different angle.

It would have been obvious to one having an ordinary skill in the art at the time of the invention was made to modify the robots arm of Sundar et al and providing the flipping feature as taught by Matsukawa et al for the purpose of providing the ability for testing system to test the wafer from different angle

Regarding claim 2, Becker et al discloses (fig 1) the members (93) comprises a plurality of wedge assemblies (15, 12) configured to rotate the substrate (20) about the first axis

Art Unit: 2829

Regarding claim 3, Becker et al discloses (fig 1) the first axis is disposed generally perpendicular to a flat surface of the substrate (20) and extends generally through an axial center of the substrate.

Regarding claim 4, Matsukawa et al. discloses (fig 12) the holding structure comprises tow L shaped gripping arms (111a, 111b) arranged to form a single U shape and configured to hold the substrate substantially parallel to the gripping arms

Regarding claims 5,6, Matsukawa et al discloses the U shaped structure is configured to open and close about the perimeter of the substrate (W)

Regarding claim 7, Becker et al discloses (fig 1) the holding structure (10) comprises three wedge assemblies (15, 14, 12), at least one wedge assembly coupled to a motor (not shown, column 2 line 51 - 55). and configured to rotate the substrate (20) about the first axis disposed generally perpendicular to a flat surface of the substrate (20) and extending generally through an axial center of the substrate.

Application/Control Number: 09/593,358

Art Unit: 2829

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Jimmy Nguyen at (703) 306-5858. Any inquiry of a General nature of relating to the status of this application or proceeding should be directed to the Group receptionist whose telephone number is (703) 305-4900.

JN.

Nov 20, 2002

KAMAND CUNEO

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